

In the Claims:

Please cancel claims 14-16, amend claims 17 and 19 as follows, and add new claims 20-25. The status of the claims is as follows:

1. (Withdrawn) A mold for forming an information pattern including servo information or address information on a substrate of a recording medium by pressing a concave and convex face onto the heated substrate, wherein  
the mold is made from carbon.
2. (Withdrawn) The mold according to claim 1, wherein  
said carbon is crystalline graphite whose covalent bond surface is formed perpendicularly to a pressing direction.
3. (Withdrawn) A mold for forming an information pattern including servo information or address information on a substrate of a recording medium by being pressed onto the heated substrate, comprising:  
a carbon plate;  
a bonding layer formed on the carbon plate; and  
a crystalline graphite plate bonded onto said bonding layer, wherein  
the crystalline graphite has a covalent bond surface that is formed perpendicularly to a pressing direction.

4. (Withdrawn) A method of manufacturing a mold for forming an information pattern including servo information or address information on a substrate of a recording medium by being pressed onto the heated substrate, comprising the steps of:

forming a mask corresponding to said information pattern on a carbon plate;  
etching said carbon plate in areas on which said mask is not formed; and  
removing said mask.

5. (Withdrawn) A method of manufacturing a mold for forming an information pattern including servo information or address information on a substrate of a recording medium by being pressed onto the heated substrate, comprising the steps of:

subjecting a crystalline graphite plate to cleavage;  
forming a mask corresponding to said information pattern on the crystalline graphite plate having been subjected to the cleavage;  
etching said crystalline graphite plate in areas on which said mask is not formed; and  
removing said mask.

6. (Withdrawn) The method of manufacturing a mold according to claim 5, further comprising the steps of:

bonding a carbon plate on a rear face of an etched surface of said crystalline graphite plate with a bonding layer being interpolated in between.

7. (Withdrawn) A method of manufacturing a mold for forming an information pattern including servo information or address information on a substrate of a recording medium by being pressed onto the heated substrate, comprising the steps of:

forming a resist pattern corresponding to said information pattern on a carbon plate;

forming a metal film on said carbon plate and resist;

lifting the resist formed on said carbon plate off together with the metal film formed on the resist;

etching the carbon plate using the metal film formed on said carbon plate as a mask; and

removing the metal film formed on said carbon plate.

8. (Withdrawn) A method of manufacturing a mold for forming an information pattern including servo information or address information on a substrate of a recording medium by being pressed onto the heated substrate, comprising the steps of:

forming a resist pattern corresponding to said information pattern on a carbon plate;

forming a second carbon layer on said carbon plate and resist; and

removing the resist formed on said carbon plate together with the second carbon layer formed on the resist.

9. (Withdrawn) A method of manufacturing a mold for forming an information pattern including servo information or address information on a substrate of a recording medium by being pressed onto the heated substrate, comprising the steps of:

forming a metal film on a carbon plate;

forming a resist pattern corresponding to said information pattern on the metal film;

etching said metal film in areas on which no resist pattern is formed;

etching said carbon plate using the metal film formed on said carbon plate as a mask; and

removing the metal film formed on said carbon plate and the resist on the metal film.

10. (Withdrawn) The method of manufacturing a mold according to claim 4, wherein,

the mask is formed and the outer or inner periphery of said carbon plate is cut, with said carbon plate being firmly fastened onto a supporting base.

11. (Withdrawn) The method of manufacturing a mold according to claim 7, wherein,

the resist pattern is formed and the outer or inner periphery of said carbon plate is cut, with said carbon plate being firmly fastened onto a supporting base.

12. (Withdrawn) The method of manufacturing a mold according to claim 8, wherein,

the resist pattern is formed and the outer or inner periphery of said carbon plate is cut, with said carbon plate being firmly fastened onto a supporting base.

13. (Withdrawn) The method of manufacturing a mold according to claim 9, wherein,

the resist pattern is formed and the outer or inner periphery of said carbon plate is cut, with said carbon plate being firmly fastened onto a supporting base.

14-16. (Canceled)

17. (Currently amended) A substrate of a recording medium comprising:  
a glass layer; and  
~~an information pattern including servo information or address information, formed on a surface of said glass layer, said surface having concave and convex shapes of a concave and convex face of a carbon mold used to form said information pattern on said surface,~~

wherein said information pattern is formed by pressing the face of the carbon mold on said glass layer when said glass layer is heated.

18. (Previously Presented) A substrate according to claim 17, wherein the carbon of mold is crystalline graphite whose covalent bond surface is formed perpendicularly to a pressing direction.

19. (Currently Amended) A substrate of a recording medium comprising:  
a glass layer; and  
~~an information pattern including servo information or address information,~~  
formed on a surface of said glass layer, said surface having concave and convex shapes of a  
concave and convex face of a carbon mold used to form said information pattern on said  
surface,

wherein said information pattern is formed by pressing said face of said carbon  
mold on said glass layer when said glass layer is heated;

the mold comprising:

a carbon plate;

a bonding layer formed on the carbon plate; and

a crystalline graphite plate bonded onto said bonding layer,

the crystalline graphite having a covalent bond surface that is formed  
perpendicularly to a pressing direction.

20. (New) A method for fabricating a substrate of a recording medium,  
comprising:

heating a glass layer; and

pressing a carbon mold on said glass layer to form concave and convex shapes  
of an information pattern on a surface of said glass layer, said carbon mold having a face  
including concave and convex shapes corresponding to said concave and convex shapes  
formed on said glass layer.

21. (New) The method according to claim 20, wherein said information pattern includes servo information or address information.

22. (New) A method according to claim 20, wherein the carbon mold is crystalline graphite whose covalent bond surface is formed perpendicularly to a pressing direction.

23. (New) The method according to claim 20, wherein said carbon mold is manufactured by:

forming a resist pattern corresponding to said information pattern on a carbon plate;

forming a metal film on said carbon plate and said resist pattern;  
lifting said resist pattern off said carbon plate together with said metal film formed on said resist pattern;

etching the carbon plate using the metal film formed on said carbon plate as a mask; and

removing the metal film formed on said carbon plate.

24. (New) The method according to claim 20, wherein said carbon mold is manufactured by:

forming a resist pattern corresponding to said information pattern on a carbon plate;

forming a second carbon layer on said carbon plate and said resist pattern; and

removing said resist pattern formed on said carbon plate together with the second carbon layer formed on the resist.

25. (New) The method according to claim 20, wherein said carbon mold is manufactured by:

forming a metal film on a carbon plate;

forming a resist pattern corresponding to said information pattern on said metal film;

etching said metal film in areas on which no resist pattern is formed;

etching said carbon plate using said metal film formed on said carbon plate as a mask; and

removing said metal film and said resist pattern.